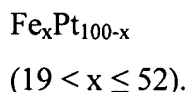


## AMENDMENTS TO THE CLAIMS

**1 to 8. (Canceled)**

**9. (New)** An FePt magnetic thin film having an atomic composition represented by the following Formula:



**10. (New)** The FePt magnetic thin film according to Claim 9, having a thickness of less than 100 nm and an  $L1_0$  structure.

**11. (New)** The FePt magnetic thin film according to Claim 9, being formed on a single crystalline substrate or on an oxide undercoat layer formed on the surface thereof.

**12. (New)** The FePt magnetic thin film according to Claim 11, being formed via a thin layer of one or more of transition and noble metals formed as an undercoat layer.

**13. (New)** The FePt magnetic thin film according to Claim 12, wherein the thin layer is a single layer or multiple layers.

**14. (New)** The FePt magnetic thin film according to Claim 13, wherein the thin layer has a layer of one or more of Fe, Ag, Ni, Co and Cr and a layer of one or more of Au, Pt, and Cu.

**15. (New)** A method of producing the FePt magnetic thin film according to claim 9, characterized by forming the FePt magnetic thin film by sputtering on a single crystalline substrate, a substrate having an oxide undercoat layer formed thereon, or a substrate having a thin layer of one or more of transition and noble metals as undercoat layer at a temperature in the range of 240°C to 500°C.

**16. (New)** The method of producing the FePt magnetic thin film according to Claim 15, wherein the FePt magnetic thin film is formed by sputtering at a temperature of 300°C or lower.